

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : PATENT APPLICATION
FISCHIONE ET AL. :
Serial No.: To be assigned : **METHOD AND APPARATUS FOR
PREPARING SPECIMENS FOR
MICROSCOPY**
Filed August 1, 2003

INFORMATION DISCLOSURE STATEMENT

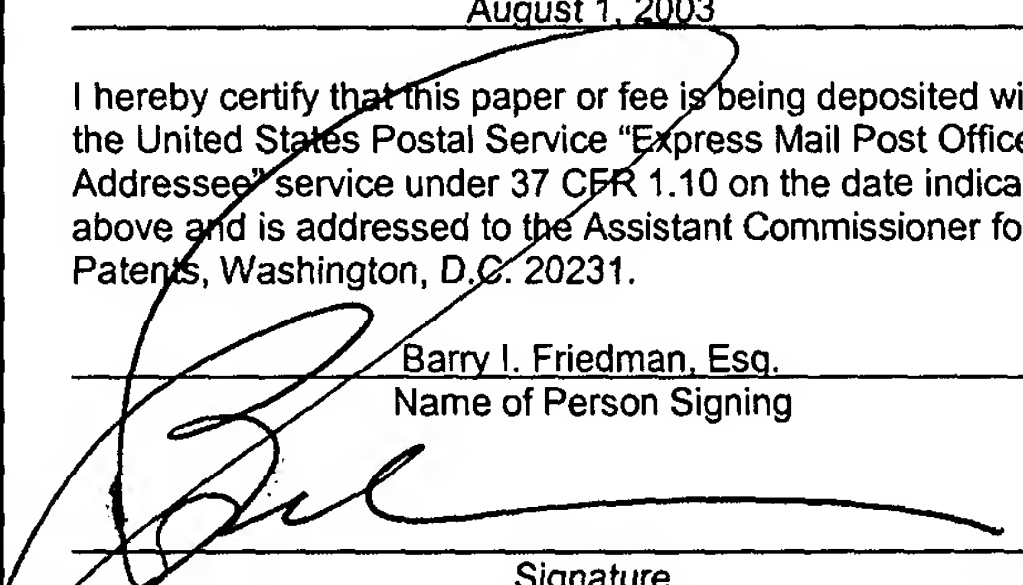
Pittsburgh, Pennsylvania 15222

August 1, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. §§1.51, 1.56, 1.97 and 1.98, a copy of the art identified on attached form PTO-1449 is enclosed herewith as a citation in connection with the captioned application. The applicants hereby request the Examiner to review and make an independent evaluation of the art. A copy of each reference is provided.

Express Mail mailing label number:
EV 068576799US
Date of Deposit:
August 1, 2003
I hereby certify that this paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR 1.10 on the date indicated above and is addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.
Barry I. Friedman, Esq. Name of Person Signing
 Signature

Koch, et al. United States Patent No. 3,958,124

Fischione, United States Patent No. 5,633,502

Subramanian, et al., United States Patent No. 6,190,062

Model 682, Precision Etching Coating System (PECS), Gatan Inc., 2001

Ion Beam Sputter Deposition and Etching System IBS/e, downloaded from the Internet at http://www.southbaytech.com/cgi-bin/homepage/products/view_product.cfm.

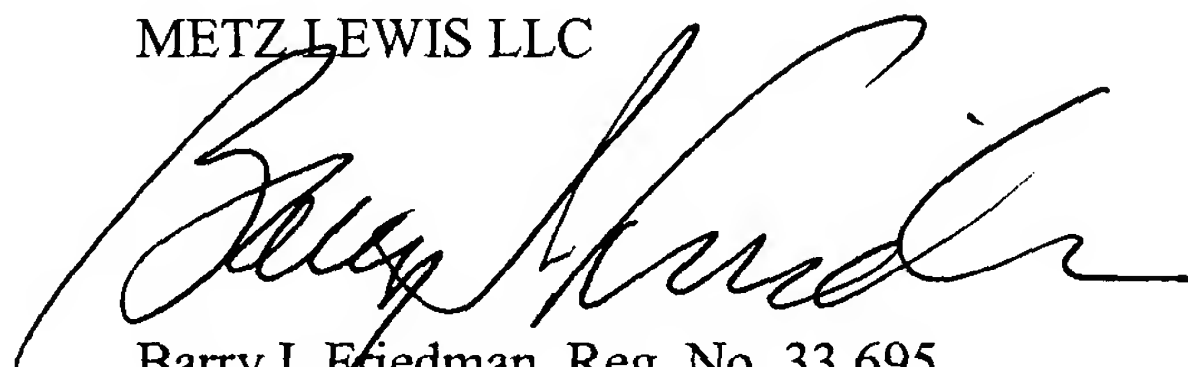
Recent Advances in Broad Ion Beam Techniques/Instrumentation for SEM Specimen Preparation of Semiconductors, Alani R., Mitro, R.J., Hauffe, W., Proceeding from the 25th International Symposium for Testing and Failure Analysis, November 1999.

No fee is believed to be required in connection with the filing of this Information Disclosure Statement because it is being submitted prior to the mailing of a first office action on the merits in the above-captioned application.

Applicants believe that their METHOD AND APPARATUS FOR PREPARING SPECIMENS FOR MICROSCOPY as described and claimed in the present application is neither taught nor suggested by this art. Accordingly, applicants' invention is believed to be patentable over these references.

Respectfully submitted,

METZ LEWIS LLC

A handwritten signature in black ink, appearing to read "Barry I. Friedman", is written over the printed name and address below.

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INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				ATTY DOCKET NO. 129/015		SERIAL NO. To be assigned	
				Fischione et al.			
				FILING August 1, 2003		GROUP	

U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		3,958,124	5/18/76	Koch et al.			
		5,633,502	5/27/97	Fischione			
		6,190,062	2/20/01	Subramanian et al.			

FOREIGN PATENT DOCUMENTS								
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>			
			Model 682, Precision Etching Coating System (PECS), Gatan Inc., 2001
			Ion Beam Sputter Deposition and Etching System IBS/e, downloaded from the Internet at http://www.southbaytech.com/cgi-bin/homepage/products/view_product.cfm .

EXAMINER	DATE CONSIDERED
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

			Recent Advances in Broad Ion Beam Techniques/Instrumentation for SEM Specimen Preparation of Semiconductors, Alani R., Mitro, R.J., Hauffe, W., Proceeding from the 25th International Symposium for Testing and Failure Analysis, November 1999

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